

ABSTRACT OF THE INVENTION

The present invention provides a standardized facilities box having a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility (i.e., a pedestal for supporting a semiconductor processing tool, or a support a pedestal of a support grid for a raised floor useable in a semiconductor device fabrication facility). The standardized facilities box includes one or more mechanisms that allow any of a set of add on features to be selectively coupled (i.e., for attachment at predetermined locations without machining) thereto. Other aspects include a facilities box having its own support leg, having a sensor, and/or having a lift/lower mechanism for lifting the facilities box or for lifting items to/from the facilities box.